Maarten P. de Boer, updated Nov. 1, 2007

Journal Publications:
(502 citations according to Web of Science)

32. F. W. DelRio, M. L. Dunn and M. P. de Boer, *Capillary adhesion model for contacting micromachined surfaces*, **submitted**, (Oct. 2007).
31. M. P. de Boer et al., *On-chip laboratory suite for free-standing metal film mechanical property testing, Part II*, **submitted**, (Sept, 2007).
30. M. P. de Boer et al., *On-chip laboratory suite for free-standing metal film mechanical property testing, Part I*, **submitted**, (Sept, 2007).
29. A. D. Corwin and M. P. de Boer, *A linearized method to measure dynamic friction of microdevices*, **submitted**, (Sept. 2007).
28. P. C. T. de Boer and M. P. de Boer, *Rupture work of pendular bridges*, Langmuir, **in press**, (2007).
27. M. P. de Boer and P. C. T. de Boer, *Thermodynamics of capillary adhesion between rough surfaces*, J. Coll. Inter. Sci., **311**, 171-185 (2007).
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25. M. P. de Boer, *Capillary adhesion between elastically hard rough surfaces*, Exp. Mech., **47** (1), 171 (2007).
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19. F. W. DelRio, M. P. de Boer, J. A. Knapp, E. D. Reedy, P. J. Clews and M. L. Dunn, *Role of dispersion forces in adhesion of micromachined surfaces*, Nature Materials **4** (8) 629 (2005).
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